

**Applicants:** Charles J. Molnar/

[illegible]

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.


Examiner: Anthony Djini | Date considered: 2/11/05  
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Form PTO-1449 (modified by applicant)	Dock. #: 1DTLB12803	Applic #: 10/730631
Information disclosure citation in an application	Filing Date: 12/8/03	Group art unit: 3723
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### US Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
AD	6568989	5-27-03	Molnar	451	5	
	6526547	2-25-03	Breiner et al.	716	4	
	6408227	6-18-02	Singhvi et al.	700	266	
	6298470	8-2-01	Breiner et al.	716	4	
	6293851	9-25-01	Molnar	451	41	
	6291349	9-18-01	Molnar	438	609	
	6283829	9-4-01	Molnar	451	8	
	6268641	7-31-04	Yano et al	257	620	
	6267644	7-31-01	Molnar	451	41	
	6263255	7-17-01	Tan et al.	700	121	
	6257953	7-10-01	Gittis et al.	451	5	
	6197604	3-6-01	Miller	438	14	
	6157916	12-5-00	Hoffman	705	8	
	6128540	10-3-00	Van Der Vegt et al.	700	36	
	6121143	9-19-00	Messner et al.	438	692	
	6056781	5-2-00	Wassick et al.	703	12	
	6038540	3-14-00	Krist et al.	705	8	
	5993298	11-30-99	Duescher	451	56	
	5987398	11-16-99	Halverson et al.	702	179	
	5985045	11-16-99	Kobayashi	148	240	
	5972793	10-26-99	Tseng	438	692	
	5968280	10-19-99	Ronay	134	2	
	5958794	9-28-99	Bruxuort	438	692	
AD	5954997	9-21-99	Kaufman	252	79.1	
	5954975	9-21-99	Cadien	216	38	

### Foreign Patent Documents

Exam Initial	Document number	Date	Name	Class	Sub class	Filing date if approp.
AD	WO 99/64527	12-16-99	Sachan et al.	C09G	1/02	
	WO 98/08919	3-5-98	Kalota et al.	C10M	A2	
	WO 00/00567	1-6-00	Kaufman et al.	C09K	3/14	
AD	WO 00/00561	1-6-00	Kaufman et al.	C09G	1/02	

Other documents (including Author, Title, Date, Pertinent pages, etc.)

AD	6204181 withdrawn from issue, Molnar, filed 11-5-99, published March 20, 2001, serial number 09/438180
AD	BERMAN, MIKE et al., "Review of in Situ and in Line Detection for CMP Applic.", Semiconductor Fabtech, 8 <sup>th</sup> edition, pp. 267-274.
AD	BIBBY, THOMAS, "Endpoint Detection for CMP", Journal of Electronic Materials, Vol. 27, #10, 1998, pp. 1073-1081.

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MD	5954347	8-31-99	Wright	438	692	
	5934978	8-31-99	Burke	451	A36	
	5919082	7-6-99	Walker	451	41	
	5916855	6-29-99	Avanzino	51	307	
	5910041	6-8-99	Duescher	451	28	
	5906754	5-25-99	Appel	216	88	
	5885334	3-23-99	Suzuki	438	639	
	5885137	3-23-99	Ploessl	106	3	
	5876490	3-2-99	Ronay	106	3	
	5876266	3-1-99	Miller	451	56	
	5860847	1-19-99	Sakurai et al.	451	10	
	5858813	1-12-99	Scherber	438	693	
	5842909	12-1-98	Sandhu	451	7	
	5833519	11-10-98	Moore	451	56	
	5830280	11-3-98	Sato	134	2	
	5799286	8-25-98	Morgan et al.	705	30	
	5783489	7-21-98	Kaufman	438	692	
	5774633	6-30-98	Baba et al.	395	23	
	5762537	6-9-98	Sandhu	451	7	
	5759917	6-2-98	Grover et al.	438	690	
	5749769	5-12-98	Church	451	5	
	5743784	4-28-98	Birang	451	21	
	5740033	4-14-98	Wassick et al.	364	149	
	5738562	4-14-98	Doan	451	5	
	5735036	4-7-98	Barr	29	603.12	
	5733819	3-31-98	Kodama	438	692	
	5733176	3-31-98	Robinson	451	41	
	5728308	3-17-98	Muroyama	216	88	
	5722879	3-3-98	Cronin	451	281	
MD	5695660	12-9-97	Litvak	216	85	
	5695384	12-9-97	Beratan	451	28	

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AD	5691895	11-25-97	Kurtzberg et al.	364	148	
	5685766	11-11-97	Mattingly	451	36	
	5667629	9-16-97	Pan	438	13	
	5647952	7-15-97	Chen	156	636.1	
	5643060	7-1-97	Sandhu	451	285	
	5639388	6-17-97	Kimura	216	84	
	5614444	3-25-97	Farkas	437	225	
AD	5609517	3-11-97	Lofaro	451	529	

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Exam Initial	Document Number	Date	Name	Class	Sub class	Filing date if approp.

Other documents (including Author, Title, Date, Pertinent pages, etc.)

AD	"Understanding and Using Cost of Ownership", Wright Williams & Kelly, Dublin, CA, rev 0595-1
	"Intermetal Dielectric Cost-of-Ownership", Case, C.B. and Case, C. J., <u>Semiconductor International</u> , June 1995, pp 83-88
	"Using COO to select Nitride PECVD clean cycle", Anderson, Bob, et al., <u>Semiconductor International</u> , Oct. 1993, pp 86-88
	"The application of cost of ownership simulation to wafer sort and final test", Jimez, D. W. et al., SEMI's Manufacturing test Conference, July, 1993
	"Reducing Tungsten Deposition equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , Oct. 1992, pp 23-25
	"Reducing ion-implant equipment cost of ownship through in situ contamination prevention and control", Burghard, R. W., et al., <u>Microcontamination</u> , Sept. 1992, pp 27-30
	"Reducing tungsten-etch equipment cost of ownership through in situcontamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , June 1992, pp 33-36
	"Reducing process equipment cost of ownership through in situ contamination prevention and reduction", Burghard, R. W., et al., <u>Microcontamination</u> , May. 1992, pp 21-24
AD	"Cost of ownership for inspection equipment", Dance D. and Bryson, P., Sematech, Austin, Texas, date unknown

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<i>AD</i>	5609511	3-11-97	Moriyama	451	5	
	5597442	1-28-97	Chen	156	626.1	
	5595526	1-21-97	Yau	451	8	
	5537325	7-16-96	Iwakiri et al.	364	468.28	
	5521814	5-28-96	Teran et al.	364	402	
	5486995	1-23-96	Krist et al.	364	149	
	5413941	5-9-95	Koos	437	8	
	5352277	10-24-94	Sasaki	106	6	
	5340370	8-23-94	Cadien	51	38	
	5314843	5-24-94	Yu	437	225	
	5308438	5-3-94	Cote	156	636	
	5196353	3-23-93	Sandhu	437	7	
	5166080	11-24-92	Schietinger	437	7	
	5154512	10-13-92	Schietinger	374	9	
	5137544	8-11-92	Medillin	51	308	
	5107445	4-21-92	Jensen	36	525	
	5069002	12-3-91	Sandhu	51	165R	
	5023045	6-11-91	Watanabe et al.	376	215	
	4544375	10-1-85	Rehmat et al.	48	197	
	4421068	12-20-83	Aral	122	448	
	2003/0093762	5-15-03	Reitman et al.	716	2	
	2003/0083757	5-1-03	Card et al.	700	28	
<i>AD</i>	2002/0123818	9-5-02	Yamada et al.	700	121	
	2002/0010563	1-24-02	Ratteree et al.	703	2	

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